

Mail Stop: After Final
PATENT
8007-1118

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Masaru HOSOKAWA et al.	Conf. 4713
Application No. 10/594,567	Group 1793
Filed September 27, 2006	Examiner S. Abu Ali

MATERIAL FOR CHEMICAL VAPOR DEPOSITION
AND THIN FILM FORMING METHOD

AMENDMENT AFTER FINAL REJECTION

Assistant Commissioner for Patents	June 12, 2009
P.O. Box 1450	
Alexandria, VA 22313-1450	

Sir:

In response to the Official Action mailed March 12, 2009, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 6 of this paper.